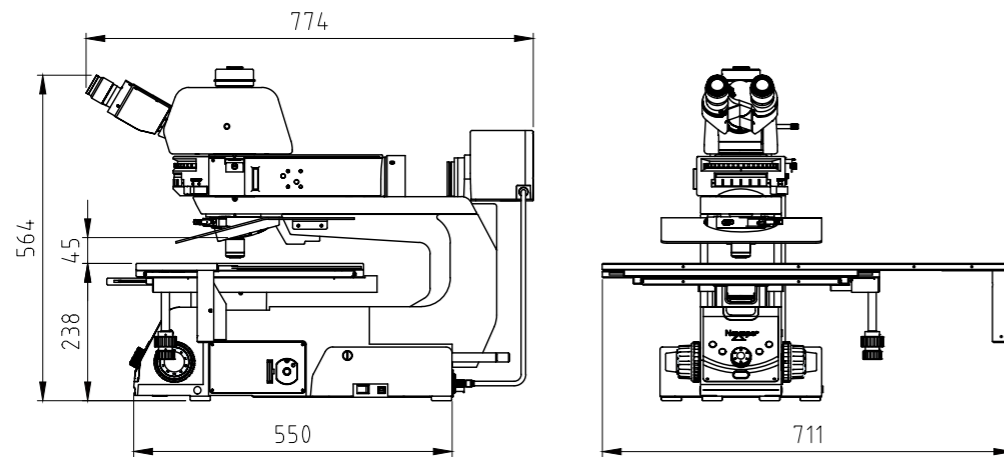


NX1000

Main Body	Optical system	NIS45 Infinite optical system
	Eyepiece	· SW10x(25) · SW10X(22) · EW12.5X(17.5) · WF15X(16) · WF20X(12)
	Focusing system	Coaxial focusing mechanism with low position With height stop loop,slack adjuster and left to right micromotion handwheel exchange mechanism Focusing range 32mm, Fine-tuning lattice value 1um
Eyepiece Tube		· Siedentopf trinocular viewing head Eyepiece/port:100/0、20/80、0/100 Depression angle:30 degrees,pupil distance adjustment range:47-78mm · Ergo tilting trinocular viewing head Eyepiece/port:100/0、20/80、0/100 Depression angle:0-30 degrees, pupil distance adjustment range:47-78mm
Nosepiece		Sextuple nosepiece for bright and dark field, with DIC slot (Auto)
Stage		Large Stage 14" x 12" Range: 356 x 305 mm (Lighting area for transmitted light:356 x 284 mm) It can be used for 300mm wafers,attached is the sample bracket.
Condenser		Transmitted illuminatin with condenser
Observation methods	EPI illumination	Bright field ,dark field ,DIC, simplified polarized, and fluorescent
	Transillumination	Bright field, simplified polarized light

DIMENSION FIGURE

(Unit: mm)



Nexcope[®]
Scientific research microscope

Nexcope[®]
Scientific research microscope

Industrial Inspection Microscope

NX1000 Series



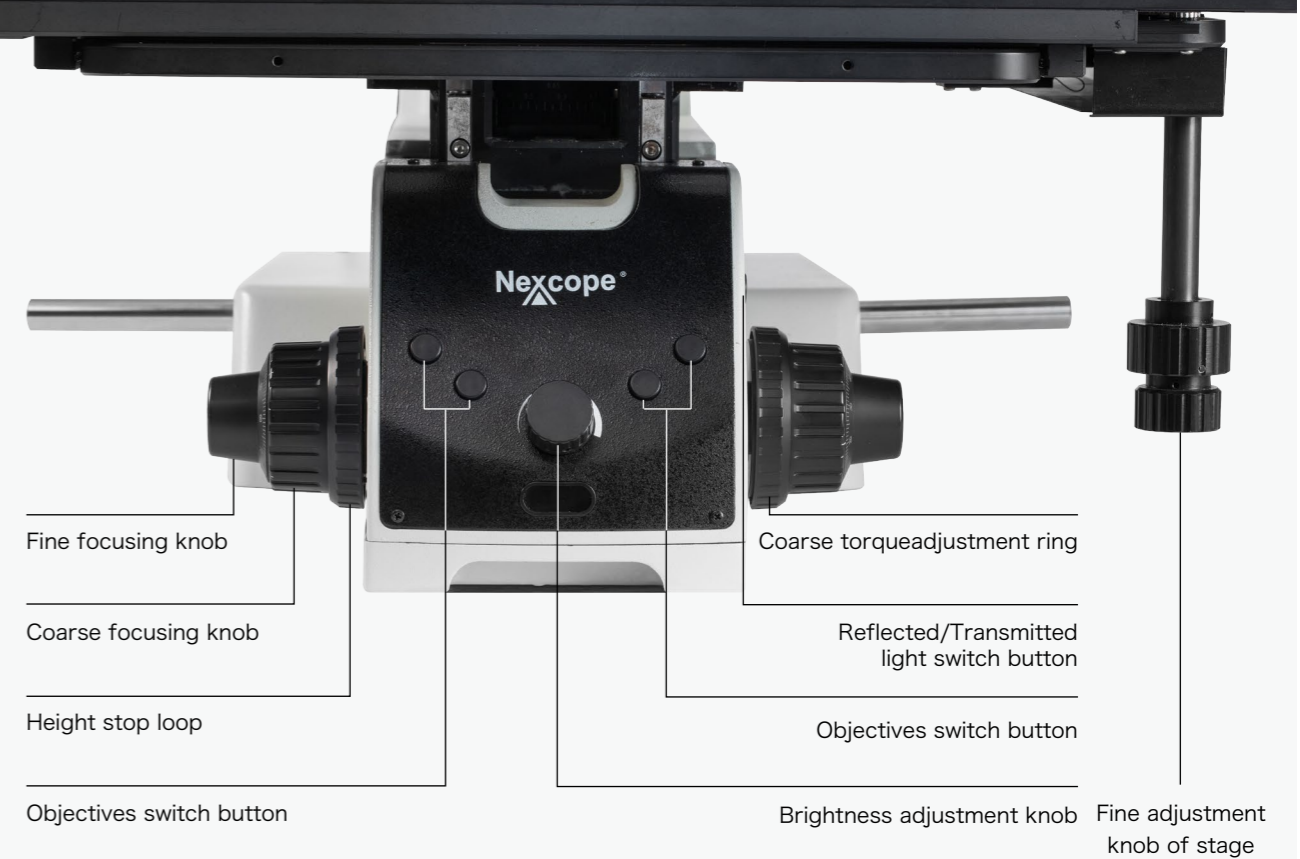
INDUSTRIAL INSPECTION MICROSCOPE

Industrial Inspection Microscope NX1000 Series

Used for microelectronics and semiconductor inspection



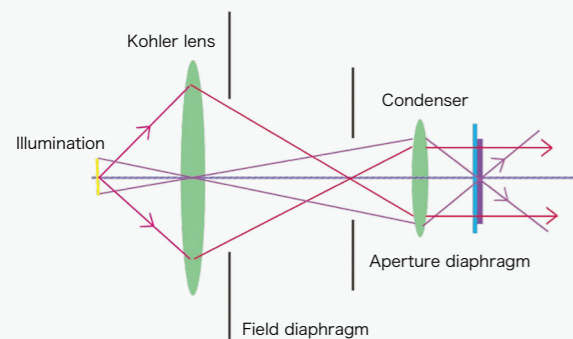
“Near Operator” design



The operating panel of the microscope is located on the front of the microscope.

The control mechanism used for observation is located on the front of the microscope (near the operator), which makes the operation on the microscope more quickly and conveniently when observing the sample. And it can reduce the fatigue caused by long time observation and the floating dust brought by a big range of movement.

High imaging reduction



Kohler lens

Perfect microscopic illumination system — Kohler illumination, provides bright and uniform illumination throughout the viewing field. Coordinated with infinity optical system NIS45, high NA and LWD objective, perfect microscopic imaging can be provided.

NIS45 series objective

By adopting multilayer coating technology, NIS45 series objective lens can compensate spherical aberration and the chromatic aberration from ultraviolet to near infrared. The sharpness, resolution and color rendition of the images can be guaranteed. The image with high-resolution and flat image for various magnifications can be got.

Humanized design



Ergo tilting trinocular viewing head

The Ergo tilting viewing head can make the micro-observation work more comfortable, so as to minimize the muscle tension and discomfort caused by long hours of work.

Focusing mechanism and fine adjustment handle of stage with low hand position

The focusing mechanism and fine adjustment handle of stage adopt the low hand position design, which conforms to the ergonomic design, and gives the greatest degree of comfortable feeling.

More convenient for industrial sample observation

High imaging reduction



The built-in clutch handle of stage

It can realize the fast and slow moving mode of the stage and can quickly locate large-area samples. It will no longer be difficult to locate the samples accurately and quickly when co-using with the fine adjustment handle of stage.



Built-in control panel

The specific button is set to correspond with a specific objective, and then the magnification can be changed easily by one click.

More suitable for FPD and LSI sample



Oversized stage

The areas of microelectronics and semiconductor samples tend to be large, so ordinary metallographic microscope stage cannot meet their observation needs. NX1000 has a oversized stage with a large movement range, and it is convenient and easy to move. So it is an ideal tool for microscopic observation of large area industrial samples.



Anti - static protective cover

Industrial samples should be far away of floating dust, and a bit of dust can affect product quality and test results. NX1000 has a large area of anti - static protective cover, which can furthest prevent from the floating dust and fall dust so as to protect the samples and make the test result more accurate.

Longer working distance and high NA objective

All kinds of electronic components and semiconductors make the circuit board samples have a larger difference in height. Therefore, special objective with long working distance are adopted in this microscope. Meanwhile, in order to satisfy the industrial samples' high requirements on color reproduction, the multilayer coating technology has been developed and improved over the years and the apochromatic objective with high NA are adopted, which can restore the real color of samples.



NIS 45 objective

Ordinary microscope

Modular design

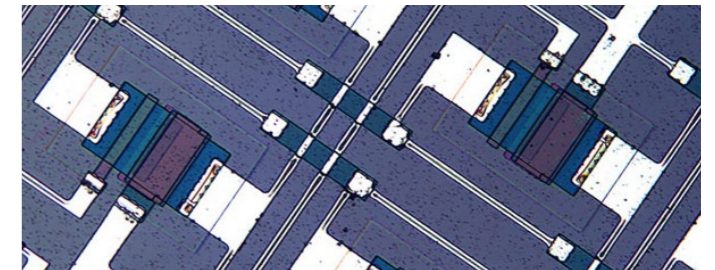
	Bright field	Dark field	DIC	Fluorescent light	Polarized light
Reflected illumination	○	○	○	○	○
Transmitted illumination	○	-	-	-	○

Nexcope research-grade microscopes can realize a variety of observation methods through modular combination: bright field, dark field, phase contrast, fluorescence, polarization, DIC and so on.

A variety of observation methods can meet various testing requirements.

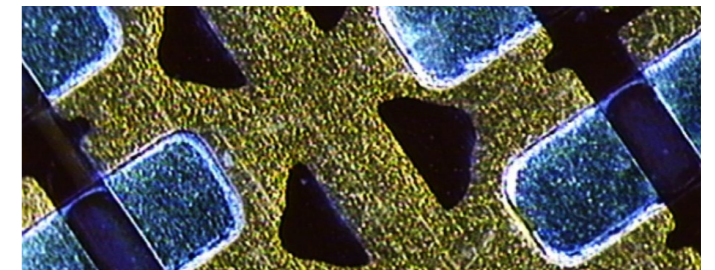
Reflected illumination bright field

NX1000 adopts an excellent NIS infinity optical system. The viewing field is uniform, bright and with high color reproduction degree. It is suitable to observe opaque semiconductor samples.



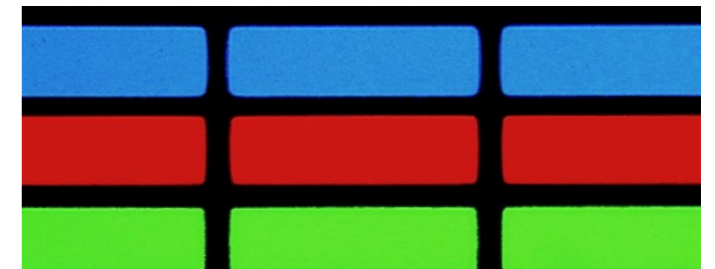
Dark field

It can realize bright observation at dark field observation and carry on high sensitivity inspection to the flaws such as fine scratches. It is suitable for surface inspection of samples with high demands.



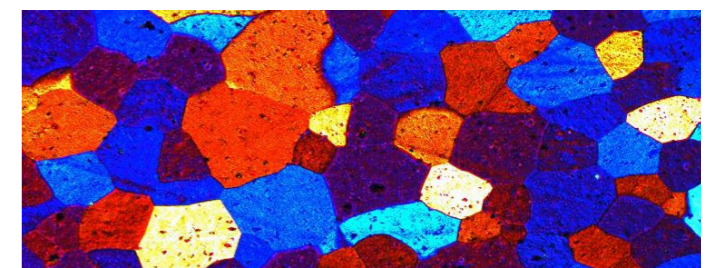
Bright field of transmitted illumination

For transparent samples, such as FPD and optical elements, the bright field observation can be realized by condenser of transmitted light. It can also be used with DIC, simple polarization and other accessories.



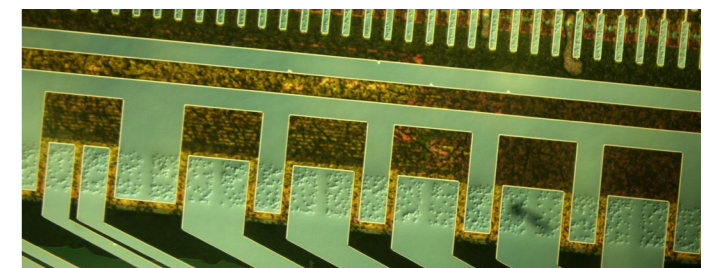
Simple polarization

This observation method is suitable for birefringence specimens such as metallurgical tissues, minerals, LCD and semiconductor materials.



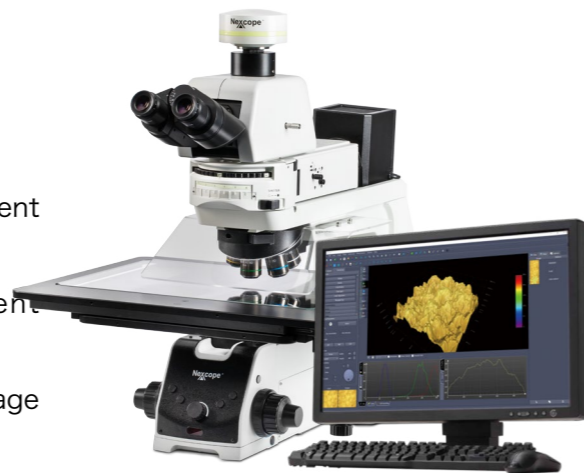
Reflected illumination DIC

This method is used to observe small differences in precision molds. The observation technique can show the subtle height difference which cannot be seen in an ordinary observation way in the form of embossment and three-dimensional images.



NOMIS Basic image processing system

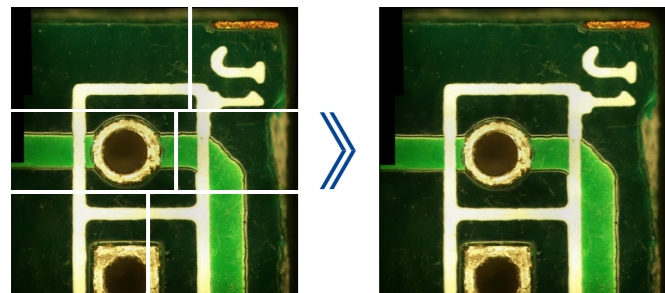
- The software has various functions to satisfy your different image processing and analysis needs.
- Multiple cameras are available to provide excellent microscopic photographing scheme.
- The universal USB3.0 interface provides high-speed image transmission.



Imaging software with high quality image acquisition, processing and analysis

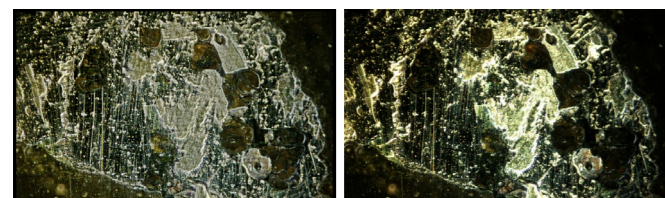
Image stitching

NOMIS Basic can quickly assemble small images into a large, high-resolution image by collecting images or importing images in real time.



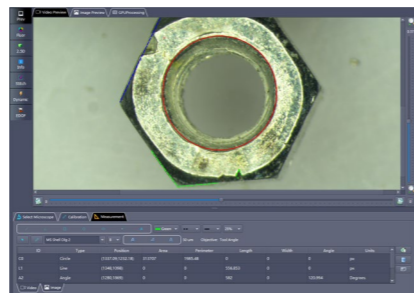
HD real-time HDR image/video

When different samples are observed, the surface of the sample shows a high-contrast area. HDR enables users to create a perfect exposure image between clicks.



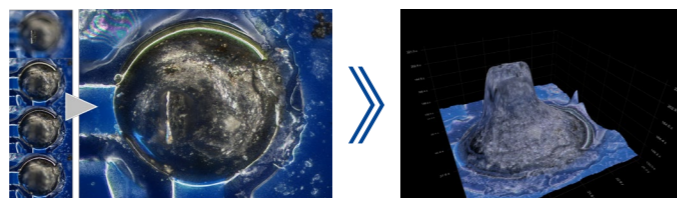
Real-time/static measurement

Typical observation and quality control require interactive measurement function. For example: distance, angle, rectangle, circle and ellipse.



Depth of field fusion / 3D reconstruction

NOMIS Basic provides depth of field fusion and 3D reconstruction functions.



The camera can be selected according to the observation demand.



High resolution refrigeration color camera
TC6CCD
1 inch, 6 million pixels CCD



High resolution color camera
T6CCD
1 inch, 6 million pixels CCD



High speed color camera
T16
4/3 inch, 16 million pixel CMOS

System diagram

Used for Nexcope NX1000 series microscope

